

PATENT ASSIGNMENT COVER SHEET

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 Stylesheet Version v1.2

EPAS ID: PAT3738487

SUBMISSION TYPE:	NEW ASSIGNMENT	
NATURE OF CONVEYANCE:	ASSIGNMENT	
CONVEYING PARTY DATA		
	Name	Execution Date
	SCIOCS COMPANY LIMITED	01/20/2016
RECEIVING PARTY DATA		
Name:	SUMITOMO CHEMICAL COMPANY, LIMITED	
Street Address:	27-1, SHINKAWA 2-CHOME, CHUO-KU	
City:	TOKYO	
State/Country:	JAPAN	
Postal Code:	104-8260	
PROPERTY NUMBERS Total: 13		
Property Type	Number	
Application Number:	12003231	
Application Number:	12222907	
Application Number:	13137202	
Application Number:	13137689	
Application Number:	13569983	
Application Number:	14831514	
Application Number:	13615421	
Application Number:	13794522	
Application Number:	13746860	
Application Number:	13781568	
Application Number:	14163967	
Application Number:	12591423	
Application Number:	14212821	
CORRESPONDENCE DATA		
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<i>Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.</i>		
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ATTORNEY DOCKET NUMBER:	HIR
NAME OF SUBMITTER:	SEAN M. MCGINN
SIGNATURE:	/Sean M. McGinn/
DATE SIGNED:	02/12/2016
Total Attachments: 3 source=AssignmentofApplications#page1.tif source=AssignmentofApplications#page2.tif source=AssignmentofApplications#page3.tif	

ASSIGNMENT OF APPLICATION FOR PATENT

4060505
c/A 4060505

WHEREAS

NAME AND ADDRESS
OF ASSIGNOR

SCIOCS COMPANY LIMITED
880 Isagozawa-cho, Hitachi-shi
Ibaraki-ken, 319-1418 JAPAN

(HEREINAFTER REFERRED TO AS ASSIGNOR), owns
certain new and useful inventions entitled:

TITLES OF INVENTIONS: (PLEASE SEE ATTACHED LIST)

WHEREAS

FULL NAME AND ADDRESS
OF ASSIGNEE

SUMITOMO CHEMICAL COMPANY, LIMITED
27-1, Shinkawa 2-chome, Chuo-ku
Tokyo 104-8260, JAPAN

(hereinafter referred to as ASSIGNEE), is desirous of
acquiring the entire right, title, and interest in, to and
under said inventions and the United States Letters
Patents to be obtained therefor.

NOW THEREFORE, TO ALL WHOM IT MAY CONCERN:

Be it known that in consideration of the payment of
ASSIGNEE to ASSIGNOR of the sum of One Dollar (\$1.00),
the receipt of which is hereby acknowledged, and for other
good and valuable consideration, ASSIGNOR, by these
presents, hereby sells, assigns and transfers to ASSIGNEE
the entire and exclusive right, title and interest to said
inventions and all Letters Patents of the United States to be
obtained therefor on said applications or any continuation,
division, renewal, substitute or reissue thereof for the full
term or terms for which the same may be granted.

ASSIGNOR hereby authorizes and requests the
Commissioner of Patents and Trademarks to issue said
Letters Patents of the United States Patents obtained
therefor on said applications or any continuation, division,
renewal, substitute or reissue thereof for the full term or
terms to said ASSIGNEE, of the entire right, title, and
interest in and to the same, for his sole use and behoof,
and for the use and behoof of his legal representatives, to
the full end of the term or terms for which said Letters
Patents obtained therefor on said applications or any
continuation, division, renewal, substitute or reissue
thereof for may be granted, as full and entirely as the same
would have been held by ASSIGNOR had this assignment
and sale not been made.

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ASSIGNOR hereby covenants that no assignment, sale, agreement or encumbrance has been or will be made or entered into which would conflict with this assignment and sale; and

ASSIGNOR further covenants that ASSIGNEE will, upon its request, be provided promptly with all pertinent facts and documents relating to said applications, said inventions and said Letters Patents as may be known and accessible to ASSIGNOR and will testify as to the same in any interference or litigation related thereto and will promptly execute and deliver to ASSIGNEE or its legal representative any and all papers, instruments or affidavits required to apply for, obtain, maintain and enforce said applications, said inventions and said Letters Patents which may be necessary or desirable to carry out the purposes hereof.

DATE OF SIGNING

IN WITNESS WHEREOF, I/We have hereunto set
hand and seal this 20th day of January, 2016.

SIGNATURE

By: M. Kobayashi

Printed Name: Masahiko Kobayashi

Title: President
SCIOCS COMPANY LIMITED

WITNESSES

M. Shibata

T. Sawto

(Assignment of Application for Patent -- page 2 of 2)

Docket No.	Application No.	Present Status	Title of Invention
PHCF-07121	12/003231	Pending	Method for producing group III Nitride single crystal
PHCF-06005-CON	12/222907	Pending	NITRIDE-BASED SEMICONDUCTOR SUBSTRATE AND SEMICONDUCTOR DEVICE
PHCF-11042US	13/137202	Pending	Method for manufacturing a piezoelectric film wafer, piezoelectric film element, and piezoelectric film device
PHCF-11043US	13/137689	Pending	Method for manufacturing a piezoelectric film wafer, piezoelectric film element, and piezoelectric film device
PHCF-12048US	13/569983	Pending	METAL CHLORIDE GAS GENERATOR, HYDRIDE VAPOR PHASE EPITAXY GROWTH APPARATUS, AND NITRIDE SEMICONDUCTOR TEMPLATE
PHCF-12048US-DIV1	14/831,514	Pending	METAL CHLORIDE GAS GENERATOR, HYDRIDE VAPOR PHASE EPITAXY GROWTH APPARATUS, AND NITRIDE SEMICONDUCTOR TEMPLATE
PHCF-12056US	13/615421	Pending	NITRIDE SEMICONDUCTOR GROWTH SUBSTRATE AND MANUFACTURING METHOD OF THE SAME, NITRIDE SEMICONDUCTOR EPITAXIAL SUBSTRATE AND NITRIDE SEMICONDUCTOR ELEMENT
PHCF-13005US	13/794522	Pending	METAL CHLORIDE GAS GENERATOR, HYDRIDE VAPOR PHASE EPITAXY GROWTH APPARATUS, AND METHOD FOR FABRICATING A NITRIDE SEMICONDUCTOR TEMPLATE
PHCF-12127US	13/746860	Pending	PIEZOELECTRIC ELEMENT AND PIEZOELECTRIC DEVICE
PHCF-12145US	13/781568	Pending	GALLIUM NITRIDE SUBSTRATE AND OPTICAL DEVICE USING THE SAME
PHCF-12075US-DIV1	14/163967	Pending	NITRIDE SEMICONDUCTOR CRYSTAL PRODUCING METHOD
PHCF-09102US	12/591423	Pending	NITRIDE SEMICONDUCTOR FREE-STANDING SUBSTRATE, METHOD OF MANUFACTURING THE SAME AND NITRIDE SEMICONDUCTOR DEVICE
PHCF-14010US	14/212821	Pending	PIEZOELECTRIC THIN-FILM ELEMENT, PIEZOELECTRIC SENSOR AND VIBRATION GENERATOR